EXHIBIT F

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(12) **United States Patent**
Stirton

(10) **Patent No.: US 6,836,691 B1**
(45) **Date of Patent: Dec. 28, 2004**

(54) **METHOD AND APPARATUS FOR FILTERING METROLOGY DATA BASED ON COLLECTION PURPOSE**

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(*) Notice: Subject to any disclaimer, the term of this patent is extended or adjusted under 35 U.S.C. 154(b) by 0 days.

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(51) **Int. Cl.**[7] **G06F 19/00**
(52) **U.S. Cl.** **700/108**; 702/85
(58) **Field of Search** 700/108, 95, 110, 700/117; 702/85; 709/108, 320; 712/228; 714/25, 54; 438/12; 345/708

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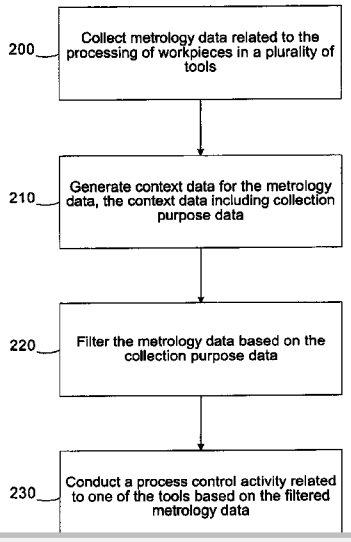
(57) **ABSTRACT**

A method includes collecting metrology data related to the processing of workpieces in a plurality of tools. Context data for the metrology data is generated. The context data includes collection purpose data. The metrology data is filtered based on the collection purpose data. A process control activity related to one of the tools is conducted based on the filtered metrology data. A system includes at least one metrology tool, a computer, and a process controller. The metrology tool is configured to collect metrology data related to the processing of workpieces in a plurality of tools. The computer is configured to generate context data for the metrology data, the context data including collection purpose data. The process controller is configured to filter the metrology data based on the collection purpose data and conduct a process control activity related to one of the tools based on the filtered metrology data.

20 Claims, 2 Drawing Sheets



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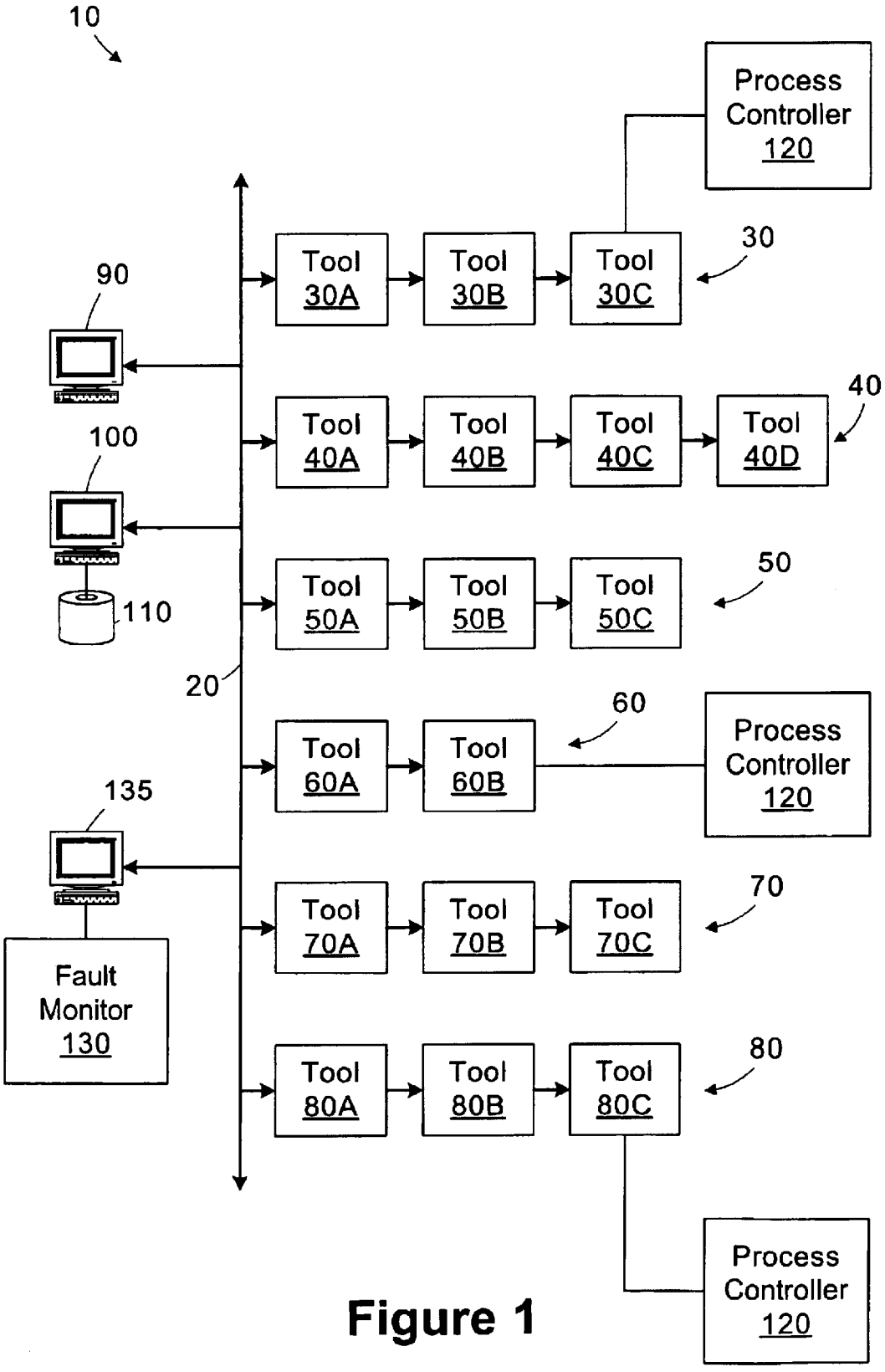

Figure 1

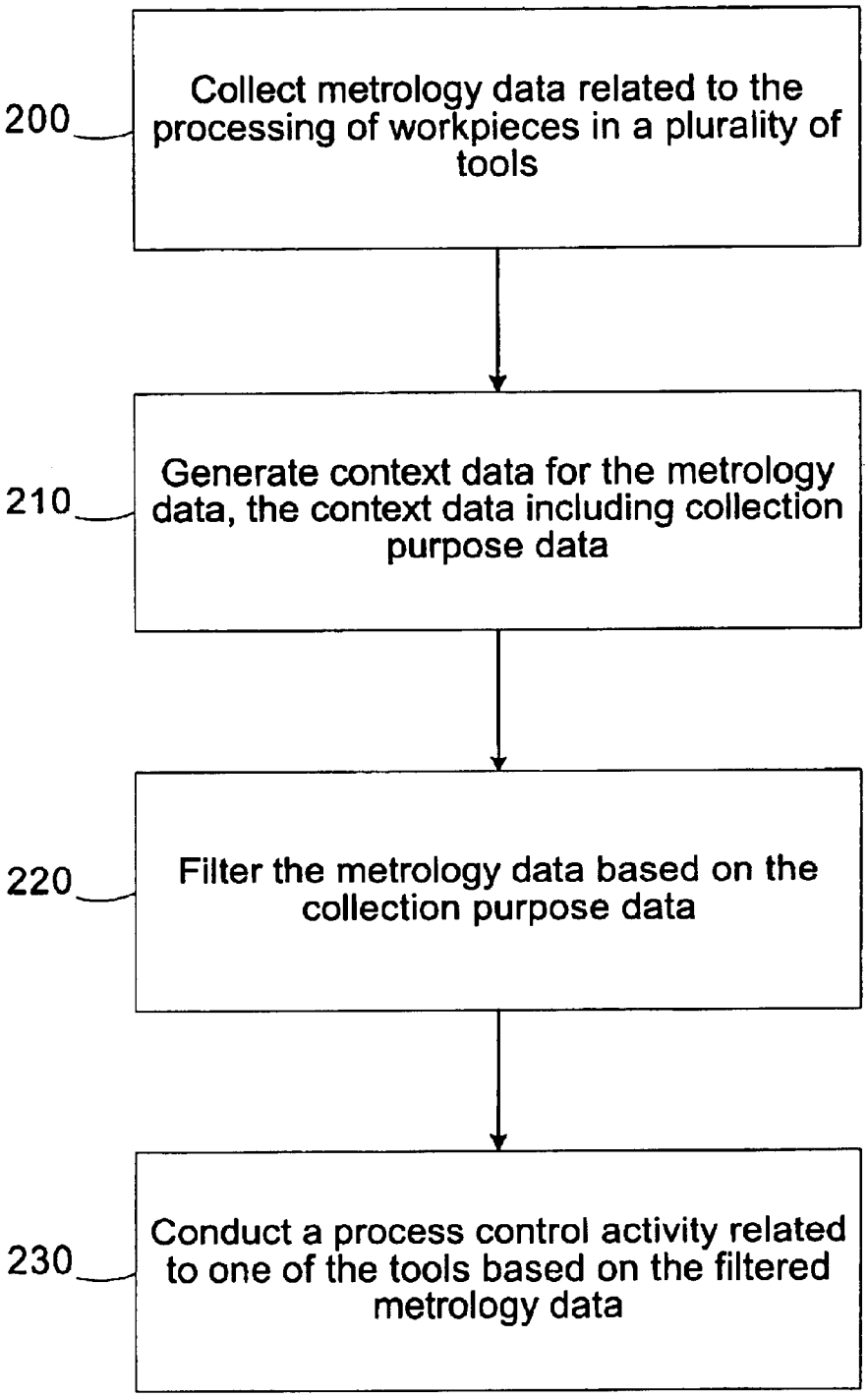

Figure 2

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